

## Supplementary Information

### **Enhancing Thermoelectric Performance for ZnO Epitaxial Films by Ga Doping and Thermal Tuning**

*Zhifang Zhou<sup>1</sup>, Guang-Kun Ren,<sup>2\*</sup> Xing Tan<sup>1</sup>, Rui Liu<sup>1</sup>, Chan Liu<sup>1</sup>, Yuan-Hua Lin,<sup>1\*</sup>  
Ce-Wen Nan<sup>1</sup>*

- 1- State Key Laboratory of New Ceramics and Fine Processing, School of Materials Science and Engineering, Tsinghua University, Beijing, 100084, P. R. China
- 2- Institute of Materials, China Academy of Engineering Physics, Jianguyou, Sichuan, 621908, P. R. China

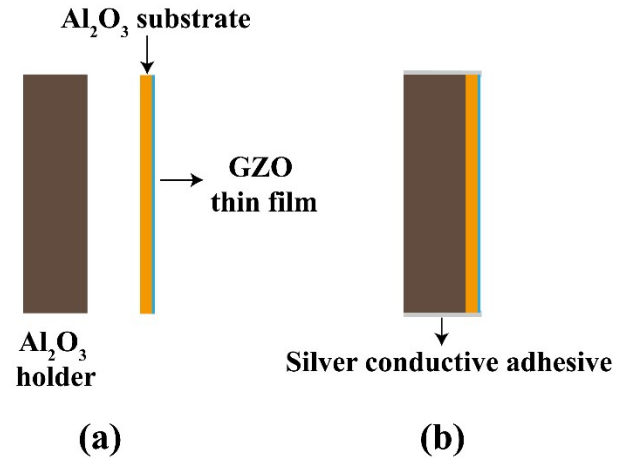
**\*Corresponding author:**

Prof. Yuan-Hua Lin E-mail: [linyuh@tsinghua.edu.cn](mailto:linyuh@tsinghua.edu.cn)

Dr. Guang-Kun Ren E-mail: [thurgk@163.com](mailto:thurgk@163.com)

#### **Measurement details of ZEM-3**

The electrical properties of samples in this work were measured by a commercial machine, ZEM-3 (ULVAC-RIKO, Japan). To measure  $\sigma$  and  $S$  from 300 K to 623 K under a helium atmosphere using the ZEM-3, the films will be firstly fixed to a homemade Al<sub>2</sub>O<sub>3</sub> ceramic holder on both ends by smearing silver conductive adhesive, and then put in an oven at 323 K for 5 min, as shown in **Fig. S1 (ESI)**. After that, the  $\sigma$  and  $S$  values could be measured by the four-probe method, and the settings are almost the same as usual, except the setting of thickness for samples. The thickness is the real thickness of thin film measured by AFM.



**Fig. S1** Preparing samples for measuring electrical properties by using ZEM-3